ABSTRACT OF THE DISCLOSURE

STAGE APPARATUS, LITHOGRAPHY APPARATUS, SUBSTRATE DELIVERY METHOD, AND ARTICLE MANUFACTURING METHOD

A stage apparatus includes a substrate chuck configured to attract and hold a substrate, a pin configured to be able to attract and hold the substrate, the pin being configured to be able to protrude from the substrate chuck through a hole in the substrate chuck, a driving portion configured to move one of the substrate chuck and the pin relative to the other of the substrate chuck and the pin, and a control portion configured to control the driving portion, wherein in a case where the substrate and the substrate chuck separate from each other, the control portion controls the driving portion based on a first condition related to easiness of separation between the substrate and the substrate chuck.

(Figure 8)